

3 Piezo Scanner 39-48

3.1



Compact series

Compact Structure, Capacitive Sensor Feedback

41

3.1.1

S series, single axis, long travel range

S100.xyz.C, S100.z.C, S300.x.C...

43

3.1.2

SD series, high dynamic

SD15.x.C, SD30.x.C...

47

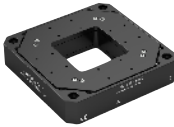
3.1.3

SH series, high load

SH30.xyz.C

48

3.2



Clear Aperture series

Versatile Stage, Multi Degrees of Freedom, Capacitive Sensor Feedback

49-64

3.2.1

Carrer.OB series, Objective Scanner

Carrier.OB100.C, Carrier.OB200.C, Carrier.OB400.C

51

3.2.2

Carrier.S series

Carrier.S100, Carrier.S200, Carrier.S300

55

3.2.3

Carrer.SL series

Carrier.SL200

62

3.3



Piezo Scanner Controller

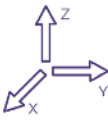
63-64

S, SH & SD Series

Compact Design, Capacitive Sensor Close-loop Control

Multi Degrees of Freedom, Travel Range up to 500 μm , High Dynamic and High Load optional

Standard

1 Axis		S100.X.C 100 μm	S300.X.C 300 μm	S500.X.C 500 μm
		S100.Z.C 100 μm	S300.Z.C 300 μm	
2 Axes		S100.XY.C 100 μm , 100 μm	S300.XY.C 300 μm , 300 μm	S500.XY.C 500 μm , 500 μm
3 Axes		S100.XYZ.C 100 μm , 100 μm , 100 μm	S200.XYZ.C 200 μm , 200 μm , 200 μm	

* Non-magnetic, Ultra High Vacuum Versions available

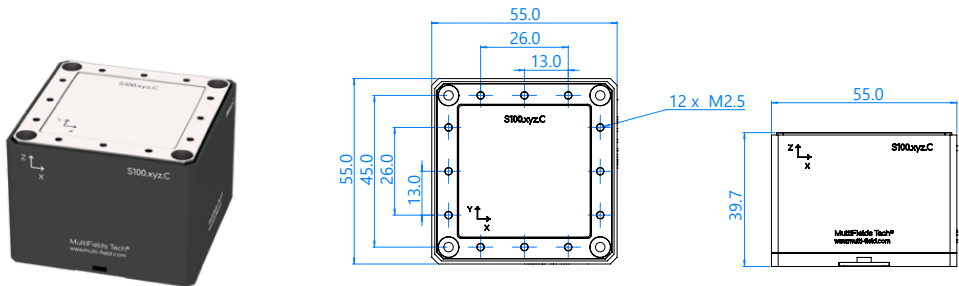


XY/XYZ Piezo Scanner — S100.XY/XYZ, S200.XY/XYZ

Compact XYZ Stack System

- Feature
- Piezo Stack Driving
 - Direct Metrology
 - Flexure Guiding
 - Sub-nanometer Resolution
 - CAP Sensor, Close-loop Control
 - Compact Serial Structure

➤ Photo & Drawing



➤ Specification

S100.XY.C

S200.XY.C

S100.XYZ.C

S200.XYZ.C

1	Optional	.NM, Non-magnetic; .HV, High Vacuum Version; .UHV, Ultra High Vacuum Version;			
2	Motion Direction	X, Y		X, Y, Z	
3	Footprint × Height	55 × 55 × 27 mm	55 × 55 × 30 mm	55 × 55 × 40 mm	55 × 55 × 45 mm
4	Material	Aluminum, Stainless Steel			
5	Travel Range (Open-loop)	120 × 120 μm	240 × 240 μm	120 × 120 × 120 μm	240 × 240 × 240 μm
6	Travel Range (Close-loop)	100 × 100 μm	200 × 200 μm	100 × 100 × 100 μm	200 × 200 × 200 μm
7	Resolution (Open-loop)	0.2 nm	0.4 nm	0.2 nm	0.4 nm
8	Resolution (Close-loop)	1 nm	1.5 nm	1 nm	1.5 nm
9	Linearity	0.03%			
10	Resonant Frequency (X/Y/Z no load)	400 / 350 / – Hz	300 / 250 / – Hz	400 / 350 / 300 Hz	300 / 250 / 200 Hz
11	Stiffness	0.5 N/μm	0.25 N/μm	0.5 N/μm	0.25 N/μm
12	Sensor Type	Capacitive			
13	Driving Voltage	Max. 150 V			
14	Working Temperature	15 ~ 40 °C			
15	Cable	D-Sub 3W3			
16	Controller	MC-Archimedes.N			

* For detail drawing and 3D model please contact us.

XYZ Piezo Scanner — S100.XYZ.C.P

Ultra Compact XYZ Stack System

➔ Feature

- Piezo Stack Driving
- Direct Metrology
- Flexure Guiding
- Sub-nanometer Resolution
- CAP Sensor, Close-loop Control
- Parallel Motion

➔ Photo & Drawing



➔ Specification

S100.XYZ.C.P

1	Optional	.NM, Non-magnetic; .HV, High Vacuum Version; .UHV, Ultra High Vacuum Version;
2	Motion Direction	X, Y, Z
3	Footprint × Height	40 × 40 × 40 mm
4	Material	Aluminum, Stainless Steel
5	Travel Range (Close-loop X/Y/Z)	100 × 100 × 100 μm
6	Linearity	0.03%
7	Resolution (Close-loop)	1 nm
8	Repeatability (X/Y/Z)	10 nm
9	Resonant Frequency (X/Y/Z no load)	700 / 700 / 700 Hz
10	Max. Payload	200g
11	Sensor Type	Capacitive
12	Driving Voltage	Max. 150 V
13	Working Temperature	15 ~ 40 °C
15	Cable	D-Sub 3W3
16	Controller	MC-Archimedes.N

* For detail drawing and 3D model please contact us.